Piezo Z-Nanopositioning Flexure Stages

Nanometer Resolution, High Speed & Stability

FAST

PRECISE

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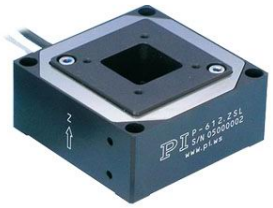
Z-Nanopositioners / Scanners

P-737 piezo Z-stage for high-resolution microscopy, fast autofocus, well plate scanning



P-612.ZSL compact nano-precision elevation stage provides 100µm Z-travel. 20x20mm aperture, closed-loop

P-733.ZCD Piezo Z-Stage, 100 µm travel, capacitive feedback for very high stability

P-62x.Z PIHera® family of nano-precision elevation stages. Z-travel 50 to 400µm. Piezo-flexure drive, capacitive feedback

PInano™ Z piezo slide scanner / fast focusing stage for high resolution microscopy

P-541 piezo Z-stage & Z-tip/tilt stage. Sub-nanometer resolution, travel to 100µm. Very low profile (16.5mm) and large 80x80mm aperture

P-611 low cost piezo Z nanopositioning stage, 100µm range, closed-loop option

PIFOC® Objective Scanner

P-737 PIFOC® Specimen-Focusing Z Stage

Low-Profile, Long-Range Piezo Z Nanopositioner for Microscopy Samples

P-737 piezo Z-stage for high-resolution microscopy

- **High-Speed Piezo Z-Motion with Travel Ranges up to 500 µm**
- **Resolution in the Nanometer Range**
- **Clear Aperture to Accomodate Specimen Holders**
- **Perfect Mechanical Fit with XY OEM Manual or Motorized Stages**
- **Sub-Millisecond Response Times**

PIFOC® P-737 high-speed vertical positioning systems are designed for use with XY microscopy stages–OEM manual stages as well as aftermarket motorized stages.

While the XY stage positions the sample, the piezo-actuator-based P-737 moves the sample along the optical axis to quickly and precisely adjust the focus. Vertical stepping with an accuracy in the nanometer range takes only a few milliseconds.

The large aperture is designed to accommodate a variety of specimen holders including slides or multiwell plates.

Application Examples

- Fluorescence microscopy
- Confocal microscopy
- Biotechnology
- Autofocus systems
- 3D Imaging
- Medical technology

High-Speed Z Steps for Fast Focus Control and Z Stack Acquisition

The immediate response of the solid-state piezo drives enables rapid Z-steps with typically 10 to 20 times faster step & settle times than classical stepper motor drives. This leads to higher image acquisition speed and throughput.

Closed-Loop Position Control for High-Precision and Stability

For high stability and repeatability, P-737 stages are equipped with position feedback. High-resolution, fast-responding, strain gauge sensors (SGS) are applied to appropriate locations on the drive train and provide a high-bandwidth, nanometer-precision position feedback signal to the controller. The sensors are connected in a full-bridge configuration to eliminate thermal drift, and assure optimal position stability in the nanometer range.

Excellent Guiding Accuracy

Flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. FEA techniques are used to give the design the highest possible stiffness in, and perpendicular to, the direction of motion, and to minimize linear and angular runout. Flexures allow extremely high-precision motion, no matter how minute, as they are completely free of play and friction.

Ordering Information

P-737.1SL
PIFOC® Nanofocusing Z-Stage for Microscope Sample Holder, 100 µm, SGS, LEMO Connector, for Märzhäuser Microscope Stages

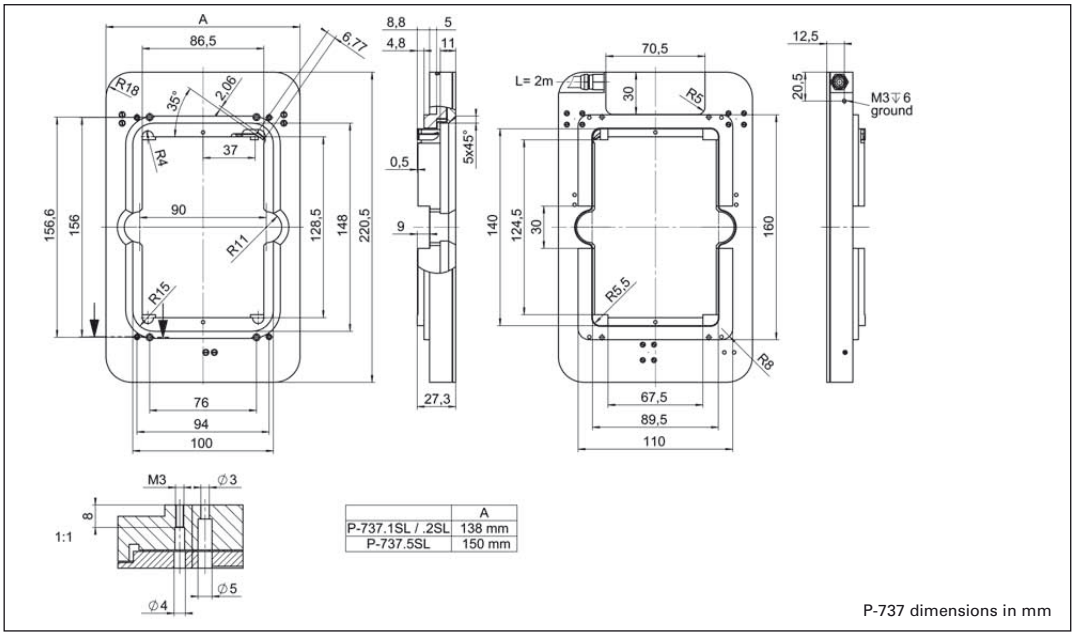
P-737.2SL
PIFOC® Nanofocusing Z-Stage for Microscope Sample Holder, 250 µm, SGS, LEMO Connector, for Märzhäuser Microscope Stages

P-737.5SL
PIFOC® Nanofocusing Z-Stage for Microscope Sample Holder, 500 µm, SGS, LEMO Connector, for Märzhäuser Microscope Stages

Versions with high-resolution capacitive sensors on request. Ask about custom designs

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.



	A
P-737.1SL / .2SL	138 mm
P-737.5SL	150 mm

P-737 dimensions in mm

The P-737 piezo Z-stage (shown with multiwell plate) is compatible with motorized microscope XY stages like the one shown from Märzhäuser

Instead of moving the sample, it is also possible to move the objective. PIFOC® Objective Scanner offers travel ranges to 1000 µm with nanometer resolution and response times in the millisecond range

N-725 PIFOC®
Objective nanofocusing system with 1 mm travel range

Technical Data

Model	P-737.1SL	P-737.2SL	P-737.5SL	Units	Tolerance
Active axes	Z	Z	Z		
Motion and positioning					
Integrated sensor	SGS	SGS	SGS		
Open-loop travel, -20 to +120 V	150	280	550	µm	min. (+20 %/-0 %)
Closed-loop travel	100	250	500	µm	
Open-loop resolution	0.8	1	1.6	nm	typ.
Closed-loop resolution	2.5	4	5	nm	typ.
Linearity, closed-loop	0.2	0.5	0.8	%	typ.
Repeatability	6	12	15	nm	typ.
Rotation around X	±36	±36	±36	µrad	typ.
Rotation around Y	±36	±100	±100	µrad	typ.
Mechanical properties					
Unloaded resonant frequency	270	210	120	Hz	±20 %
Resonant frequency @ 100 g	230	180	115	Hz	±20 %
Resonant frequency @ 200 g	210	155	100	Hz	±20 %
Push/pull force capacity in motion direction	50 / 20	50 / 20	50 / 20	N	Max.
Drive properties					
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical Capacitance	6.3	9.3	13.8	µF	±20 %
Dynamic operating current coefficient	7.9	4.6	3.5	µA/(Hz • µm)	±20 %
Miscellaneous					
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum		
Dimensions	220.5 x 138 x 27.3	220.5 x 138 x 27.3	220.5 x 150 x 27.3	mm	
Mass	0.7	0.7	0.8	kg	±5 %
Cable length	2	2	2	m	±10 mm
Sensor / voltage connection	LEMO	LEMO	LEMO		
System properties					
System configuration	E-500 System with E-503 amplifier (6 W) E-509 servo module	E-500 System with E-503 amplifier (6 W) E-509 servo module	E-665.SR controller/driver (12 W)		
Closed-loop amplifier bandwidth, small signal	60	30	15	Hz	typ.
Settling time (10 % step width)	24	30	50	ms	typ.

Recommended controller / amplifier
Single-channel: E-610 servo controller / amplifier (p. 2-110), E-625 servo controller, bench-top (p. 2-114), E-665 powerful servo controller, bench-top (p. 2-116)

PInano™ Z, Scanner for SR-Microscopy

Low-Profile, Low-Cost, Nanopositioning System for Super Resolution Microscopy

PInano™ Z nanopositioning stages (shown with optional slide and Petri dish holder) feature a very low profile of 20 mm (0.8"), a large aperture and deliver highly accurate motion with sub-nanometer resolution

- **Extremely Fast Step & Settle, From 5 msec**
- **Low Profile for Easy Integration: 20 mm (0.8")**
- **100 and 200 µm Travel Ranges**
- **Proprietary Technology: Outstanding Lifetime Due to PICMA® Piezo Ceramic Stacks**
- **Cost-Effective Design due to Piezoresistive Sensors**
- **Compatible w/ Leading Image Acquisition Software Package**
- **Closed-Loop Control for High Repeatability and Accuracy**
- **USB Controller & Software Included**

High-Speed, Low Profile, Optimized for Microscopy

The new PInano™ Z low-profile piezo Z stages are optimized for very fast step and settle and easy integration into high-resolution microscope applications. They feature a very low profile of 0.8" (20 mm), a large aperture, and travel ranges of up to 200 µm with sub-nanometer closed-loop resolution–ideal for leading-edge microscopy and imaging applications.

Application Examples

- 3D Imaging
- Scanning microscopy
- Laser technology
- Interferometry
- Metrology
- Biotechnology
- Micromanipulation

Longest lifetime is guaranteed by the integrated ceramic-encapsulated PICMA® piezo actuators. Due to the significantly higher humidity resistance, the patented PICMA® design provides up to 10 times longer life than conventional piezo actuators (see latest test results at www.pi.ws/picma).

Cost Effective Design, High Performance

PInano™ series piezo positioning stages are designed to provide high performance at minimum cost. For highly-stable, closed loop operation, piezoresistive sensors are applied directly to the moving structure and precisely measure the displacement of the stage platform. The very high sensitivity of these sensors provides optimum position stability and responsiveness as well as nanometer resolution. A proprietary servo controller significantly improves the motion linearity compared to conventional piezoresistive sensor controllers.

Excellent Guiding Accuracy

Flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. FEA techniques are used to give the design the highest possible stiffness in, and perpendicular to, the direction of motion, and to minimize linear and angular runout. Flexures allow extremely high-precision motion, no matter how minute, as they are completely free of play and friction.

Controller & Software Included

The PInano™ Z stage comes complete with a powerful digital closed-loop controller. The controller features two digital interfaces (USB & RS-232) as well as a high-speed analog interface and is compatible with leading image acquisition software packages such as MetaMorph etc.
The controllers are delivered including software for Windows operating systems. DLLs and LabVIEW drivers are available for automated control.
The extensive command set is based on the hardware-independent General Command Set (GCS), which is common to all current PI controllers for both nano- and micropositioning systems. GCS reduces the programming effort in the face of complex multi-axis positioning tasks or when upgrading a system with a different PI controller.

Ordering Information

P-736.ZR1S
PInano™ Z Piezo Slide Scanner System, 100 µm, Slide-Size Aperture, Piezoresistive Sensors, with USB Fully Digital Controller

P-736.ZR2S
PInano™ Z Piezo Slide Scanner System, 200 µm, Slide-Size Aperture, Piezoresistive Sensors, with USB Fully Digital Controller

Accessories

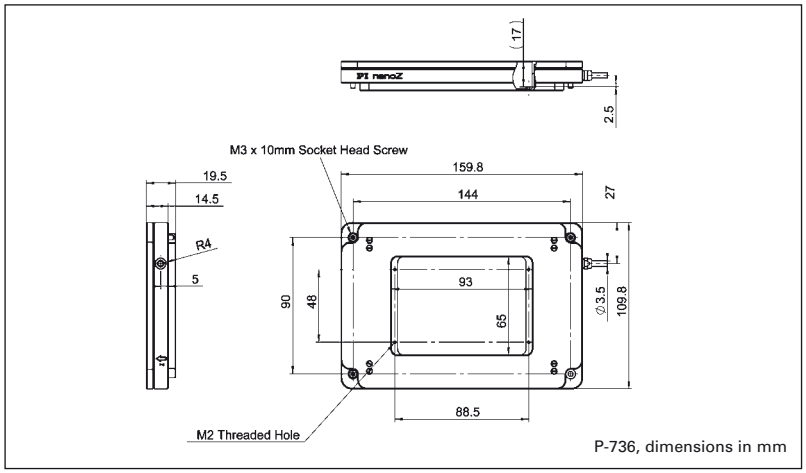
P-545.PD3
35mm Petri Dish Holder for P-545 PInano™ Piezo Stages

P-545.SH3
Microscope Slide Holder for PInano™ Piezo Stages

P-736.AP1
Adapter Plate P-736 PInano™ Piezo Z to M-545 XY Microscope Stages

The PInano™ Z stage can be combined with the M-545 high-stability, long-travel manual/motorized microscope stage (25 x 25 mm)

A compact piezo controller with a digital servo, USB, RS-232 and a high–speed analog interface is included



P-736, dimensions in mm

Technical Data

Model	P-736.ZR1S	P-736.ZR2S	Units	Tolerance
Active axes	Z	Z		
Motion and positioning				
Integrated sensor	piezoresistive	piezoresistive		
Closed-loop travel	100	200	µm	
Open-loop resolution	0.2	0.4	nm	typ.
Closed-loop resolution	0.4	0.7	nm	typ.
Linearity	±0.1	±0.1	%	typ.
Repeatability	<4	<5	nm	typ.
Mechanical properties				
Settling time (10% step width)	5	7	ms	
Load	500	500	g	max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Miscellaneous				
Operating temperature range	15 to 40	15 to 40	°C	
Material	Aluminum	Aluminum		
Mass	550	550	g	±5%
Cable length	1.5	1.5	m	±10 mm

P-733.Z High-Dynamics Piezo Z-Nanopositioning Stage

Direct Position Metrology and Clear Aperture

P-733.ZCD Piezo Z-Stage

- **Travel Range 100 µm**
- **Direct Metrology with Capacitive Sensors**
- **Resolution to 0.3 nm, Closed-Loop**
- **Clear Aperture 50 x 50 mm**
- **Versions with Additional Degrees of Freedom Available**
- **XY and XYZ Versions Also Available**
- **Vacuum-Compatible Versions Available**

P-733.Z piezo vertical stages offer a positioning and scanning range of 100 µm with sub-nanometer resolution. The 50 x 50 mm clear aperture is ideal for applications such as scanning or confocal micro - scopy. Their fast settling time of less than 10 ms allows high throughput rates.

Application Examples

- Scanning microscopy
- Confocal microscopy
- Mask / wafer positioning
- Surface measurement technique
- Nano-imprinting
- Micromanipulation
- Image processing / stablili-zation
- Nanopositioning with high flatness & straightness

Capacitive Sensors for Highest Accuracy

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity . A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz. The resolution of the P-733.Z is better than 0.3 nm.

Because of the direct measurement of the actual distance between the fixed frame and the moving part of the stage, errors in the drive train, actuator, lever arm or in guiding system do not influence the measuring accuracy. The result is exceptional motion linearity , higher long-term stability and a stiffer, more-responsive control loop, because external influences are immediately recognized by the sensor. The capacitive sensor non-linearity is typically less than 0.03 %, the repeatability of the P-733.Z is better than 2 nm.

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA ® multilayer piezo actuators. PICMA ® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.

Large Variety of Models for a Broad Range of Applications

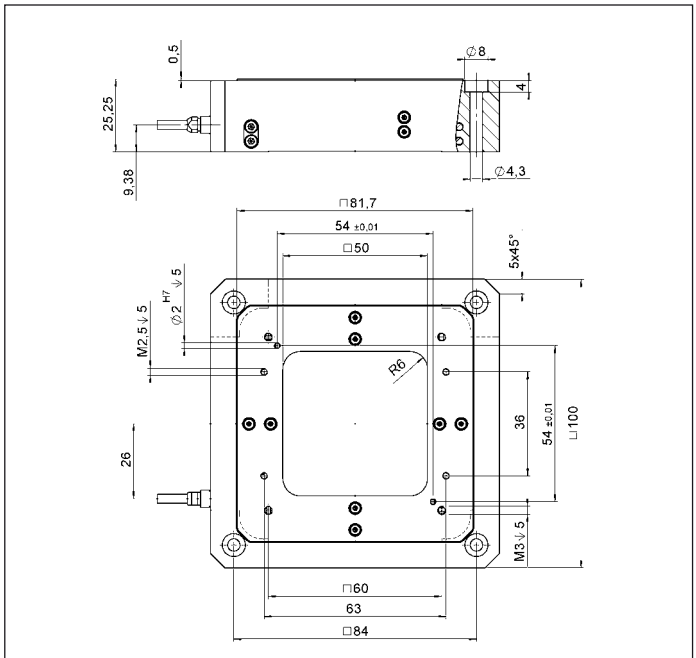
For scanning and positioning tasks in XY , the P-733.2CD and .3CD versions are available with a travel range of 100 x 100 µm. For high-dynamics applications, the P-733.2DD and P-733.3DD models can be offered with direct drive and reduced travel range (see p. 2-62).

For ultra-high-vacuum applications down to 10^{-9} hPa, nanopositioning systems as well as comprehensive accessories, such as suitable feedthroughs, are available.

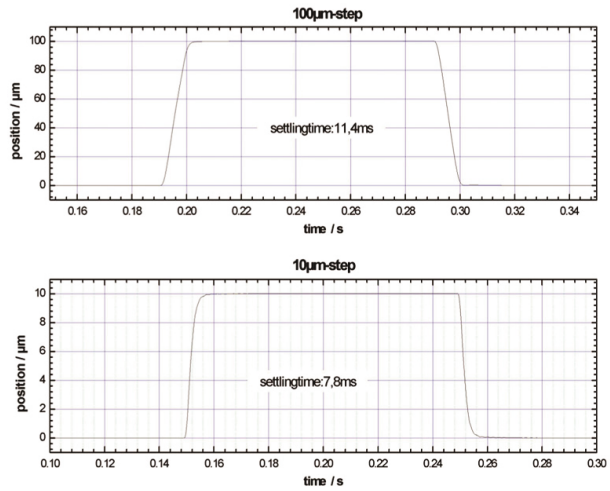
Ordering Information

P-733.ZCD
Compact Precision Nanopositioning Vertical Stage, 100 µm, Capacitive Sensor, Sub-D Connector

P-733.ZCL
Compact Precision Nanopositioning Vertical Stage, 100 µm, Capacitive Sensor, LEMO Connector



P-733.Z dimensions in mm



Step response of the P-733.ZCD. Settling time is in the 10 ms range

System properties	
System configuration	E-500 modular system with E-503 amplifier and E-509 sensor module; 20 g load
Amplifier bandwidth, small signal	96 Hz
Settling time (10 % step width)	8 ms

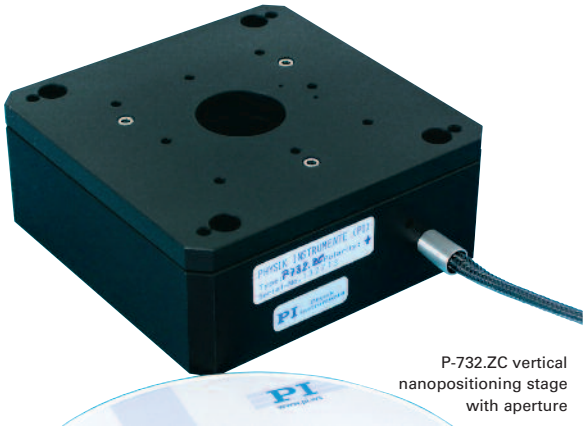
Technical Data

Model	P-733.ZCD P-733.ZCL	Tolerance
Active axes	Z	
Motion and positioning		
Integrated sensor	Capacitive	
Open-loop travel, -20 to +120 V	115 µm	min. (+20 %/-0 %)
Closed-loop travel	100 µm	
Open-loop resolution	0.2 nm	typ.
Closed-loop resolution	0.3 nm	typ.
Linearity	0.03 %	typ.
Repeatability	<2 nm	typ.
Rotation around Z	<10 µrad	typ.
Rotation around X	<5 µrad	typ.
Rotation around Y	<5 µrad	typ.
Mechanical properties		
Stiffness	2.5 N/µm	±20 %
Unloaded resonant frequency	700 Hz	±20 %
Resonant frequency @ 120 g	530 Hz	±20 %
Resonant frequency @ 200 g	415 Hz	±20 %
Push/pull force capacity	50 / 20 N	Max.
Drive properties		
Ceramic type	PICMA® P-885	
Electrical capacitance	6 µF	±20 %
Dynamic operating current coefficient	7.5 µA/(Hz • µm)	±20 %
Miscellaneous		
Operating temperature range	20 to 80 °C	
Material	Aluminum	
Dimensions	100 x 100 x 25 mm	
Mass	580 g	±5 %
Cable length	1,5 m	±10 mm
Sensor connection	Sub-D special (CD-version); 2x LEMO (CL-version)	
Voltage connection	Sub-D special (CD-version); 1 x LEMO (CL-version)	

Dynamic Operating Current Coefficient in µA per Hz and mrad. Example: Sinusoidal scan of 10 µm at 10 Hz requires approximately 3 mA drive current.
Recommended controller
One channel: E-610 controller / amplifier (p. 2-110), E-625 bench-top controller (p. 2-114), E-621 modular controller (p. 2-160)
Multi-channel: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503 (three channels) (p. 2-146) or E-505 (1 per axis, high-power) (p. 2-147) and E-509 controller (p. 2-152)
Single-channel digital controller: E-753 (bench-top) (p. 2-108)

P-732 Piezo Z-Stage with Aperture

High-Dynamics Nanopositioner / Scanner



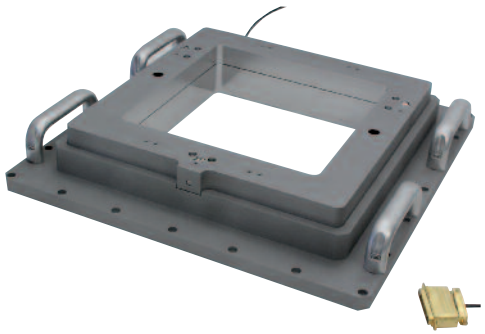
P-732.ZC vertical nanopositioning stage with aperture

- 15 µm Vertical Travel Range
- High Stiffness for Dynamic Operation
- <1 nm Resolution
- Straightness of Travel <10 µrad
- Clear Aperture with 25 mm Diameter

Model	Travel	Resolution	Linearity	Laod capacity	Rotation around Θ_X, Θ_Y
P-732.ZC	15 µm	0.1 nm	0.03 %	20 N	<10 µrad

P-915K Vacuum-Compatible Piezo-Z Stage

High-Load, High Dynamics and Large Clear Aperture



The direct-drive P-915KVPZ stage provides high stiffness for fast operation

- Travel Range 45 µm
- Large Clear Aperture 273 x 273 mm
- Direct Metrology with Capacitive Sensors
- Direct Drive for High Dynamics and Stiffness
- Vacuum Compatible up to 10^{-6} hPa
- Outstanding Lifetime Due to PICMA® Piezo Actuators

Model	Travel	Resolution	Push/ Pull force capacity	Material	Dimensions
P-915KVPZ Z Stage	45 µm	0.3 nm	20 N	Stainless stell	Moving platform: 375 x 375 mm Clear aperture: 273 x 273 mm

P-915K Low-Profile Piezo Objective Scanner

For High Scanning Frequencies

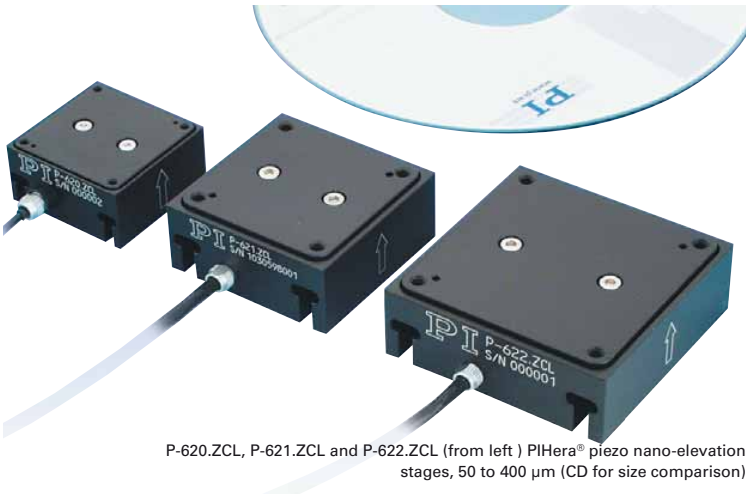
The P-915KLPZ objective scanner allows high scanning frequencies

- Very Low Profile of 15 mm
- Travel Range 75 µm
- Clear Aperture for Objectives with W0.8 x 1/36" Thread
- Frictionless, High-Precision Flexure Guiding System for Better Focus Stability and Minimized Runout
- Very Low Profile
- Outstanding Lifetime Due to PICMA® Piezo Actuators

Model	Active axes	Travel range	Resonant frequency @ 150 g	Dimensions
P-915KLPZ Objective Scanner	Z	75 µm	200 Hz	60 x 60 x 15 mm

P-620.Z – P-622.Z PIHera® Precision Z-Stage

Nanopositioning System Family with Direct Metrology and Long Travel Ranges



P-620.ZCL, P-621.ZCL and P-622.ZCL (from left) PIHera® piezo nano-elevation stages, 50 to 400 µm (CD for size comparison)

- **Vertical Travel Range 50 to 400 µm**
- **High-Precision, Cost-Efficient**
- **Resolution to 0.1 nm**
- **Direct Metrology with Capacitive Sensors**
- **0,02 % Positioning Accuracy**
- **Frictionless, High-Precision Flexure Guiding System**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **X-, XY-, Z- XYZ-Versionen**
- **Vacuum-Compatible Versions Available**

Z-axis PIHera® systems are cost-efficient piezo nanopositioning stages featuring travel ranges up to 400 µm and provide sub-nanometer resolution. Despite the increased travel ranges, the units are extremely compact and provide sub-nanometer resolution. The long travel range is achieved with a friction-free and extremely stiff flexure system, which also offers rapid response and excellent guiding accuracy.

PIHera® piezo nanopositioning stages are also available as X- and XY-stages (see p. 2-22 and p. 2-54).

Application Examples

- Interferometry
- Microscopy
- Nanopositioning
- Biotechnology
- Quality assurance testing
- Semiconductor technology

Nanometer Precision in Milliseconds

One of the advantages of PIHera® stages over motor-driven positioning stages is the rapid response to input changes and the fast and precise settling behavior. The P-622.1CD, for example, can settle to an accuracy of 10 nm in only 30 msec (other PI stages provide even faster response)!

Superior Accuracy With Direct-Metrology Capacitive Sensors

A choice of tasks such as optical path adjustment in interferometry, sample positioning in microscopy, precision alignment or optical tracking require the relatively long scanning ranges and nanometer precision offered by PIHera® nanopositioning stages.

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Designed for Precision

High stiffness is achieved with the FEA-optimized design of the frictionless flexure elements, which assure excellent guiding accuracy and dynamics. A straightness and flatness in the nanometer range is achieved.

Ordering Information

P-620.ZCD
PIHera® Precision Vertical Nanopositioning Stage, 50 µm, Capacitive Sensor, Sub-D Connector

P-620.ZCL
PIHera® Precision Vertical Nanopositioning Stage, 50 µm, Capacitive Sensor, LEMO Connector

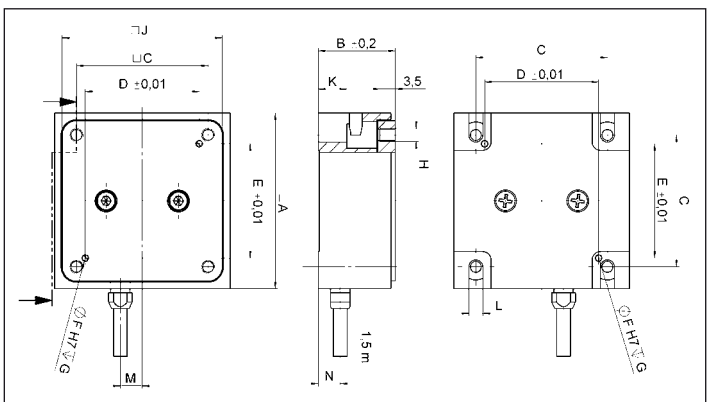
P-621.ZCD
PIHera® Precision Vertical Nanopositioning Stage, 100 µm, Capacitive Sensor, Sub-D Connector

P-621.ZCL
PIHera® Precision Vertical Nanopositioning Stage, 100 µm, Capacitive Sensor, LEMO Connector

P-622.ZCD
PIHera® Precision Vertical Nanopositioning Stage, 250 µm, Capacitive Sensor, Sub-D Connector

P-622.ZCL
PIHera® Precision Vertical Nanopositioning Stage, 250 µm, Capacitive Sensor, LEMO Connector

Open-loop versions are available as P-62x.Z0L



	A	B	C	D	E	ØF
P-620.ZCD / Z0L	30	15	24	19	24	1,01
P-621.ZCD / Z0L	40	17,5	30	26	26	1,51
P-622.ZCD / Z0L	50	17,5	40	35	35	1,51

	G	H	J	K	L	M	N
P-620.ZCD / Z0L	2	M2	28	5	2,2	4,5	6
P-621.ZCD / Z0L	2,5	M3	36,5	6,5	3,2	5	5
P-622.ZCD / Z0L	2,5	M3	46,5	6,5	3,2	5	5

P-62x.ZCD / .ZCL / .Z0L dimensions in mm

System properties	
System configuration	P-621.ZCD with E-753 digital controller and 30 g load
Amplifier bandwidth, small signal	25 Hz
Amplifier bandwidth, large signal	25 Hz
Settling time (full travel)	15 ms

PIHera® XYZ combination

Technical Data

Model	P-620.ZCD P-620.ZCL	P-621.ZCD P-621.ZCL	P-622.ZCD P-622.ZCL	P-62x.Z0L Open-loop versions	Units	Tolerance
Active axes	Z	Z	Z	Z		
Motion and positioning						
Integrated sensor	Capacitive	Capacitive	Capacitive	–		
Open-loop travel, -20 to +120 V	65	140	400	as P-62x.ZCD	µm	min. (+20 %/-0 %)
Closed-loop travel	50	100	250	–	µm	
Open-loop resolution	0.1	0.2	0.5	as P-62x.ZCD	nm	typ.
Closed-loop resolution	0.2	0.3	1	–	nm	typ.
Linearity	0.02	0.02	0.02	–	%	typ.
Repeatability	±1	±1	±1	–	nm	typ.
Runout θ_X, θ_Y)	<20	<20	<80	as P-62x.ZCD	µrad	typ.
Mechanical properties						
Stiffness	0.5	0.6	0.24	as P-62x.ZCD	N/µm	±20 %
Unloaded resonant frequency	1000	790	360	as P-62x.ZCD	Hz	±20 %
Resonant frequency @ 30 g	690	500	270	as P-62x.ZCD	Hz	±20 %
Push/pull force capacity	10 / 5	10 / 8	10 / 8	as P-62x.ZCD	N	Max.
Load capacity	10	10	10	as P-62x.ZCD	N	Max.
Lateral Force	10	10	10	as P-62x.ZCD	N	Max.
Drive properties						
Ceramic type	PICMA® P-883	PICMA® P-885	PICMA® P-885	as P-62x.ZCD		
Electrical capacitance	0.7	3	6.2	as P-62x.ZCD	µF	±20 %
Dynamic operating current coefficient	1.8	3.8	3.1	as P-62x.ZCD	µA/(Hz • µm)	±20 %
Miscellaneous						
Operating temperature range	-20 to 80	-20 to 80	-20 to 80	-20 to 150	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	0.12	0.17	0.24	as P-62x.ZCD	kg	±5 %
Cable length	1.5	1.5	1.5	as P-62x.ZCD	m	±10 mm
Sensor / voltage connection	Sub-D special (CD-version) CL-version: LEMO	Sub-D special (CD-version) CL-version: LEMO	Sub-D special (CD-version) CL-version: LEMO	LEMO (no sensor)		

Recommended controller
CD-Versions:
E-610 servo controller / amplifier (p. 2-110), E-625 servo controller, bench-top (p. 2-114), E-665 powerful servo controller, bench-top (p. 2-116)
Single-channel digital controller: E-753 (bench-top) (p. 2-108)
CL-Versions:
Modular piezo controller system E-500 (p. 2-142) with amplifier module E-505 (high performance) (p. 2-147) and E-509 controller (p. 2-152)
Open-loop versions: modular piezo controller system E-500 (p. 2-142) with amplifier module E-505 (high performance) (p. 2-147

P-612.Z Piezo Z-Stage

Compact Nanopositioning Stage with Aperture

P-612.ZSL
compact nano-elevation stage with a
20 mm x 20 mm clear aperture

- **Travel Range 100 µm**
- **Resolution to 0.2 nm**
- **Linearity 0.2 %**
- **Compact: Footprint 60 x 60 mm**
- **Very Cost-Effective Controller/Piezomechanics Systems**
- **Frictionless, High-Precision Flexure Guiding System**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**

These elevation stages are cost-effective, compact, piezo-based positioning systems with travel ranges of 100 µm. The space-saving design features a footprint of only 60 x 60 mm. The 20 x 20 mm clear aperture makes them ideally suited for sample positioning in microscopy . Equipped with PICMA® piezo drives and zero-stiction, zero-friction flexure guiding system, the series provides nanometer -range reso - lution and millisecond res - ponse time.

Application Examples

- Interferometry
- Scanning microscopy
- Nanopositioning
- Biotechnology
- Quality assurance testing
- Semiconductor fabrication

Position Servo-Control with Nanometer Resolution

High-resolution, broadband, strain gauge sensors (SGS) are applied to appropriate locations on the drive train and measure the displacement of the moving part of the stage relative to the base. The SGS sensors assure optimum position stability in the nanometer range and fast response.

The open-loop models are ideal for applications where fast response and very high resolution are essential, but absolute positioning is not important. They can also be used when the position is controlled by an external sensor such as an interferometer , a PSD (position sensitive detector), CCD chip / image processing system, or the eyes and hands of an operator.

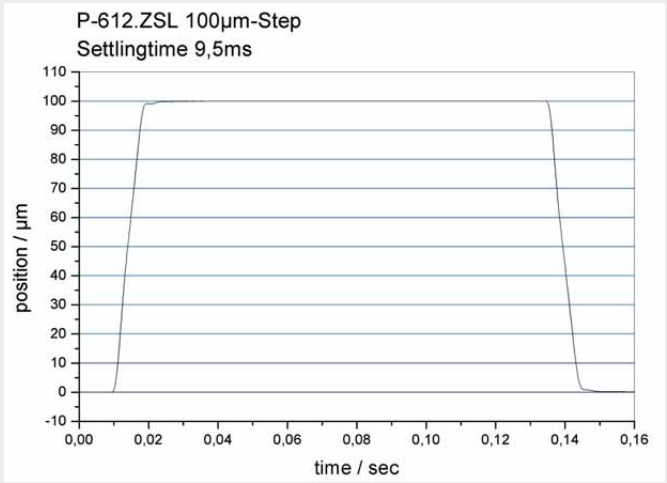
High Reliability and Long Lifetime

The compact P-612 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA ® actuators feature cofired ceramic encapsulation and thus provide better performance and reliability than conventional piezo actuators. Actuators, guiding system and sensors are maintenance-free, not subject to wear and offer an extraordinary reliability.

Ordering Information

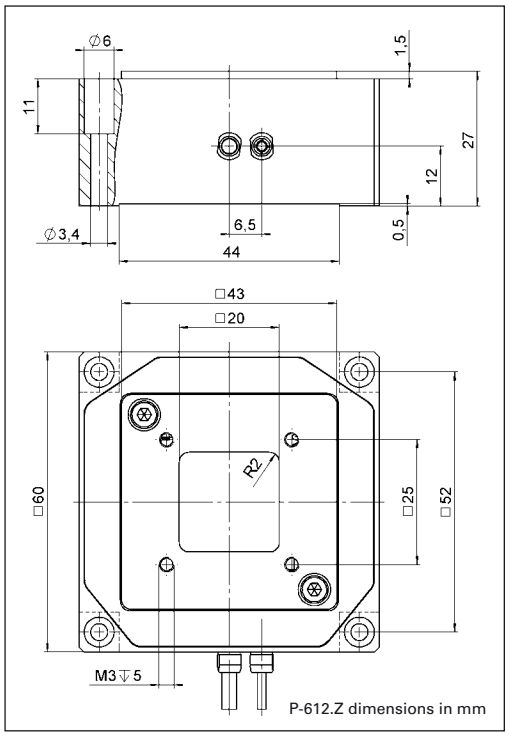
P-612.ZSL
Vertical Nanopositioning Stage, 100 µm, 20 x 20 mm Aperture, SGS-Sensor

P-612.Z0L
Vertical Nanopositioning Stage, 100 µm, 20 x 20 mm Aperture, No Sensor



Settling takes less than 10 ms over the entire travel range in closed-loop operation

P-612s are available as XY-scanners (P-612.2SL, on the left) and vertical stages (P-612.ZSL, on the right) providing a travel range of 100 µm per axis



P-612.Z dimensions in mm

System properties	
System configuration	P-612.ZSL and E-625.SR controller, 30 g load
Closed-loop amplifier small signal bandwidth	110 Hz
Closed-loop amplifier large signal bandwidth	80 Hz
Settling time (10 % step width)	8 ms

Technical Data

Model	P-612.ZSL	P-612.Z0L	Units	Tolerance
Active axes	Z	Z		
Motion and positioning				
Integrated sensor	SGS	–		
Open-loop travel, -20 to +120 V	110	110	µm	min. (+20 %/-0 %)
Closed-loop travel	100	–	µm	calibrated
Open-loop resolution	0.2	0.2	nm	typ.
Closed-loop resolution	1.5	–	nm	typ.
Linearity, closed-loop	0.2	–	%	typ.
Repeatability	±4	–	nm	typ.
Runout θ_X, θ_Y	±10	±10	µrad	typ.
Crosstalk X, Y	±20	±20	µm	typ.
Mechanical properties				
Stiffness in motion direction	0.63	0.63	N/µm	±20 %
Unloaded resonant frequency	490	490	Hz	±20 %
Resonant frequency under load	420 (30 g)	420 (30 g)	Hz	±20 %
Load capacity	15 / 10	15 / 10	N	Max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Electrical capacitance	3	3	µF	±20 %
Dynamic operating current coefficient	3.8	3.8	µA/(Hz • µm)	±20 %
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material	Aluminum	Aluminum		
Mass	0.28	0.275	kg	±5 %
Cable length	1.5	1.5	m	±10 mm
Sensor / voltage connection	LEMO	LEMO (no sensor)		

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion with E-503 amplifier. (p. 2-146)
Recommended controller / amplifier
E-610 servo controller / amplifier card (p. 2-110), E-625 servo-controller, bench-top (p. 2-114), E-665 high-power servo-controller with display, bench-top (p. 2-116), E-660 bench-top for open-loop systems (p. 2-119)

P-611.Z Piezo Z-Stage

Compact Nanopositioner

P-611 Z-axis nanopositioning stage, 100 µm closed-loop travel, resolution to 0.2 nm

- **Compact: Footprint Only 44 x 44 mm**
- **Travel Range to 120 µm**
- **Resolution to 0.2 nm**
- **Cost-Effective Mechanics/Electronics System Configurations**
- **Frictionless, High-Precision Flexure Guiding System**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **X, XY, XZ and XYZ Versions also Available**

P-611 Z stages are piezo-based nanopositioning systems with 100 µm closed-loop travel range featuring a compact footprint of only 44 x 44 mm. The stages described here are part of the P-611 family of positioners available in 1- to 3-axis configurations. Equipped with ceramic-encapsulated piezo drives and a stiff, zero-stiction, zero-friction flexure guiding system, all P-611 piezo stages combine millisecond responsiveness with nanometric precision and extreme reliability.

The P-611.Z versions described here are ideally suited for use in applications such as microscopy, auto-focusing and photonics packaging.

Application Examples

- Photonics / integrated optics
- Micromachining
- Micromanipulation
- Semiconductor testing

Closed-Loop and Open-Loop Versions

High-resolution, fast-responding, strain gauge sensors (SGS) are applied to appropriate locations on the drive train and provide a high-bandwidth, nanometer-precision position feedback signal to the controller. The sensors are connected in a full-bridge configuration to eliminate thermal drift, and assure optimal position stability in the nanometer range.

The open-loop models are ideal for applications where fast response and very high resolution are essential, but absolute positioning is not important. They can also be used when the position is controlled by an external feedback system such as an interferometer, a PSD (position sensitive diode), CCD chip / image processing system, or the eyes and hands of an operator.

Versatility & Combination with Motorized Stages

The P-611 family of piezo stages comprises a variety of single- and multi-axis versions (X, XY, Z, XZ and XYZ) that can be easily combined with a number of very compact manual or motorized micropositioning systems to form coarse/fine positioners with longer travel ranges (see p. 2-20, p. 2-50 *ff*).

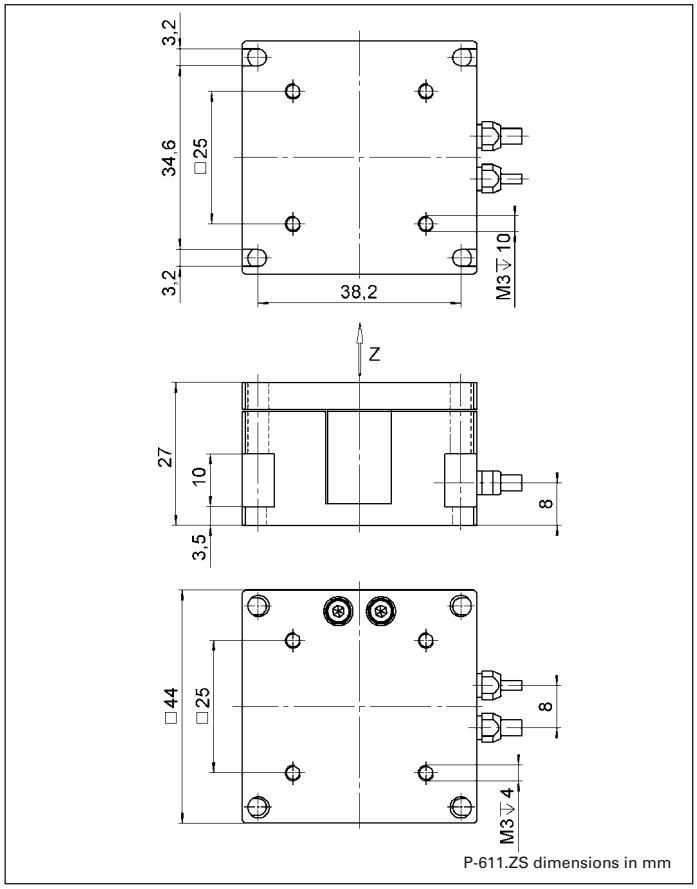
High Reliability and Long Lifetime

The compact P-611 systems are equipped with preloaded PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and thus offer better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free and not subject to wear, and thus offer an extraordinary reliability.

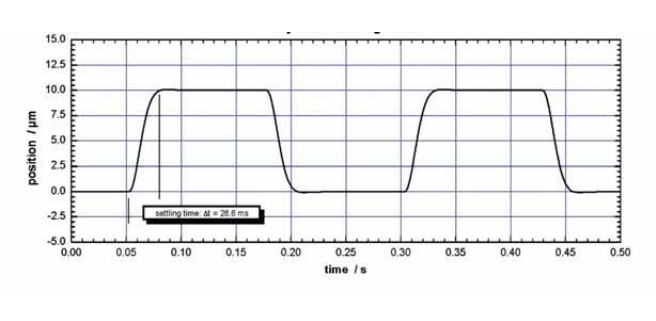
Ordering Information

P-611.Z0
Vertical Nanopositioning Stage, 120 µm, No Sensor

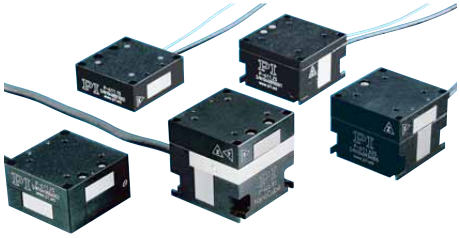
P-611.ZS
Vertical Nanopositioning Stage, 100 µm, SGS-Sensor



P-611.ZS dimensions in mm



The settling time of a P-611.Z with a load of 30 g is 26 ms for a 10 µm step. Measured with interferometer



The whole P-611 family: X, Z, XY, XZ and XYZ stages

Technical Data

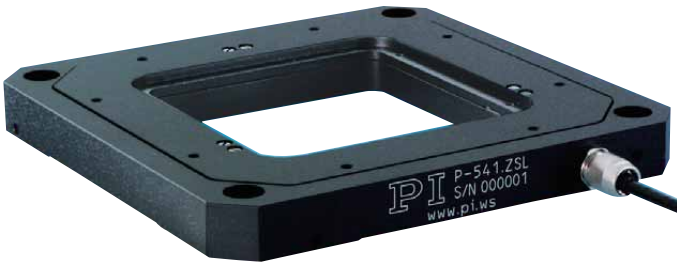
Model	P-611.ZS	P-611. Z0	Unit	Tolerance
Active axes	Z	Z		
Motion and positioning				
Integrated sensor	SGS	-		
Open-loop travel, -20 to +120 V	120	120	µm	min. (+20 %/0 %)
Closed-loop travel	100	-	µm	
Open-loop resolution	0.2	0.2	nm	typ.
Closed-loop resolution	2	-	nm	typ.
Linearity 0.1		-	%	typ.
Repeatability	<10	-	nm	typ.
Runout θZ (Z motion)	±5	±5	µrad	typ.
Runout θX (Z motion)	±20	±20	µrad	typ.
Runout θY (Z motion)	±5	±5	µrad	typ.
Mechanical properties				
Stiffness	0.45	0.45	N/µm	±20 %
Unloaded resonant frequency	460	460	Hz	±20 %
Resonant frequency @ 30 g	375	375	Hz	±20 %
Resonant frequency @ 100 g	265	265	Hz	±20 %
Push/pull force capacity	15 / 10	15 / 10	N	Max.
Drive properties				
Ceramic type	PICMA® P-885	PICMA® P-885		
Electrical capacitance	1.5	1.5	µF	±20 %
Dynamic operating current coefficient	1.9	1.9	µA/(Hz • µm)	±20 %
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material	Aluminum, steel	Aluminum, steel		
Dimensions	44 x 44 x 27	44 x 44 x 27	mm	
Mass	176	176	g	±5 %
Cable length	1.5	1.5	m	±10 mm
Sensor connector	LEMO	LEMO		
Voltage connection	LEMO	LEMO		

Resolution of PI Piezo Nano positioners is not limited by friction or stiction. Value given is noise equivalent motion with E -503 amplifier (p. 2-146)
Recommended controller / amplifier
E-610 servo controller / amplifier (p. 2-110), E-625 servo controller, bench-top (p. 2-114), E-665 powerful servo controller, bench-top (p. 2-116), E-660 bench-top for open-loop systems (p. 2-119)

System properties	
System Configuration	P-611.1S and E-665.SR controller, 30 g load
Amplifier bandwidth, small signal	40 Hz
Settling time (10 % step width)	25 ms

P-541.Z Piezo Z and Z/Tip/Tilt Stages

Low Profile, Large Aperture



P-541 series nanopositioning Z-stages and Z-tip/tilt stages offer travel ranges of 100 µm with sub-nanometer resolution. They feature a very low profile of 16.5 mm and a large 80 x 80 mm aperture. Versions with strain gauge and capacitive position feedback sensors are available

- **Low Profile for Easy Integration: 16.5 mm; 80 x 80 mm Clear Aperture**
- **Vertical and Z/Tip/Tilt Stages**
- **100 µm Travel Range, 1 mrad Tilt**
- **Parallel-Kinematics / Metrology for Enhanced Responsiveness / Multi-Axis Precision**
- **Choice of Sensors: Strain Gauge (Lower Cost) or Capacitive Sensors (Higher Performance)**
- **Outstanding Lifetime Due to PICMA® Piezo Actuators**
- **Combination with Long-Travel M-686 Microscopy Stages**

Low Profile, Optimized for Microscopy Applications

The P-541 Z stages and Z/tip/tilt stages are for ideal alignment, nano-focusing or metrology tasks in the nanometer range. They feature a very low profile of 16.5 mm, a large 80 x 80 mm aperture, and offer highly accurate motion with sub-nanometer resolution.

Application Examples

- Scanning microscopy
- Mask / wafer positioning
- Interferometry
- Metrology
- Biotechnology
- Micromanipulation

A variety of P-541 XY scanning stages with the same footprint are also available (see p. 2-60). Due to the low-profile design, the stages can easily be integrated in high-resolution microscopes.

Choice of Position Sensors

PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Alternatively, economical strain gauge sensors are available. PI uses a bridge configuration to eliminate thermal drift, and assure optimal position stability in the nanometer range.

Active and Passive Guidance for Nanometer Flatness and Straightness

Flexures optimized with Finite Element Analysis (FEA) are completely free of play and friction to allow extremely high-precision motion. The FEA techniques also optimize straightness and flatness and provide for the highest possible stiffness in, and perpendicular to, the direction of motion.

Due to the parallel-kinematics design there is only one common moving platform for all axes, minimizing mass, enabling identical dynamic behaviour and eliminiating cumulative errors. Parallel kinematics also allows for a more compact construction and faster response compared to stacked or nested designs.

Ordering Information

P-541.ZCD
Vertical Nanopositioning Stage with Large Aperture, 100 µm, Direct Metrology, Capacitive Sensors

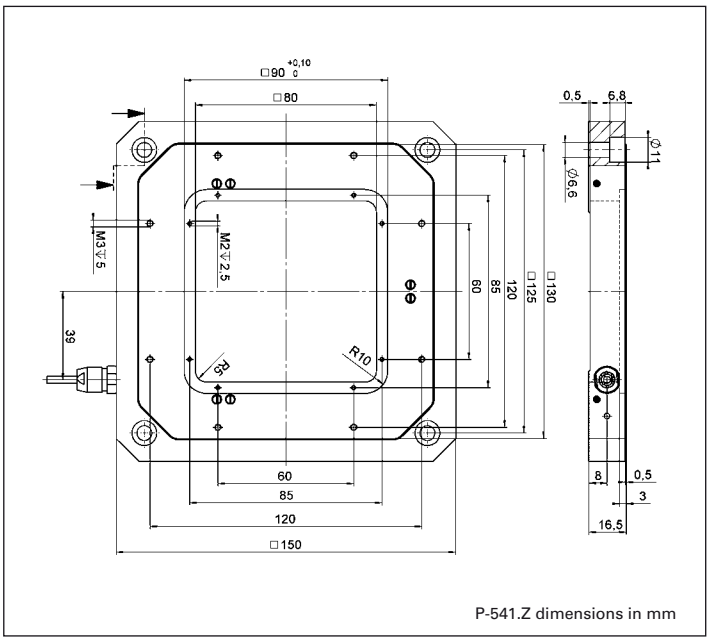
P-541.TCD
Vertical Tip / Tilt Nanopositioning Stage with Large Aperture, 100 µm / 1 mrad, Parallel Metrology, Capacitive Sensors

P-541.ZSL
Vertical Nanopositioning Stage with Large Aperture, 100 µm, Strain Gauge Sensors

P-541.TSL
Vertical Tip / Tilt Nanopositioning Stage with large Aperture, 100 µm, Strain Gauge Sensors

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.



P-541.Z dimensions in mm

M-686 open-frame stage with P-541 piezo scanner on top makes an ideal combination for microscopy tasks. The system height is only 48 mm

System properties	
System configuration	P-541.ZCD and E-500 modular system with E-503 amplifier and E-509 sensor module, 20 g load
Amplifier bandwidth, small signal	60 Hz
Settling time (10 % step width)	9 ms

Technical Data

Models	P-541.ZCD	P-541.TCD*	P-541.ZSL	P-541.TSL	P-541.T0L*	P-541.Z0L	Units	Tolerane
Active axes	Z	Z, θ_X, θ_Y	Z	Z, θ_X, θ_Y	Z	Z, θ_X, θ_Y		
Motion and positioning								
Integrated sensor	Capacitive	Capacitive	SGS	SGS	Open-loop	Open-loop		
Open-loop Z-travel, -20 to +120 V	150	150	150	150	150	150	µm	min. (+20 %/0 %)
Open-loop tip/tilt angle, -20 to +120 V	–	±0.6	–	±0.6	–	±0.6	mrad	min. (+20 %/0 %)
Closed-loop Z-travel	100	100	100	100	–	–	µm	
Closed-loop tip/tilt angle	–	±0.4	–	±0.4	–	–	mrad	
Open-loop Z-resolution	0.2	0.2	0.2	0.2	0.2	0.2	nm	typ.
Open-loop tip/tilt angle resolution	–	0.02	–	0.02	–	0.02	µrad	typ.
Closed-loop Z-resolution	0.5	0.5	2.5	2.5	–	–	nm	typ.
Closed-loop tip/tilt resolution	–	0.08	–	0.25	–	–	µrad	typ.
Linearity Z, θ_X, θ_Y	0.03	0.03	0.2	0.2	–	–	%	typ.
Repeatability Z	<2	<2	<10	<10	–	–	nm	typ.
Repeatability θ_X, θ_Y	–	0.01	–	0.05	–	–	µrad	typ.
Runout θ_X, θ_Y	±15	±15	±15	±15	±15	±15	µrad	typ.
Mechanical properties								
Stiffness Z	0.8	0.8	0.8	0.8	0.8	0.8	N/µm	±20 %
Unloaded resonant frequency (Z)	410	410	410	410	410	410	Hz	±20 %
Unloaded resonant frequency (θ_X, θ_Y)	–	330	–	330	–	330	Hz	±20 %
Resonant frequency @ 200 g (Z)	250	250	250	250	250	250	Hz	±20 %
Resonant frequency @ 200 g (θ_X, θ_Y)	–	270	–	270	–	270	Hz	±20 %
Push/pull force capacity	50 / 20	50 / 20	50 / 20	50 / 20	50 / 20	50 / 20	N	Max.
Drive properties								
Ceramic type	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885	PICMA® P-885		
Electrical capacitance	6.3	6.3	6.3	6.3	6.3	6.3	µF	±20 %
Dynamic operating current coefficient	7.9	7.9	7.9	7.9	7.9	7.9	µA / (Hz • µm)	±20 %
Miscellaneous								
Operating temperature range	20 to 80	20 to 80	20 to 80	20 to 80	20 to 80	20 to 80	°C	
Material	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum	Aluminum		
Mass	750	750	730	730	700	700	g	±5 %
Cable length	1.5	1.5	1.5	1.5	1.5	1.5	m	±10 mm
Sensoranschluss	Sub-D Special	Sub-D Special	LEMO	3 x LEMO	–	–		
Voltage connection	Sub-D Special	Sub-D Special	LEMO	3 x LEMO	LEMO	3 x LEMO		

*Parallel kinematics design; the maximum displacement for translation and tilt motion cannot be achieved at the same time
Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion with E-503 (p. 2-146) or E-710 controller (p. 2-128).
Recommended controller / amplifier
Single-channel (1 per axis): E-610 servo controller / amplifier (p. 2-110), E-625 servo controller, bench-top (p. 2-114), E-621 controller module (p. 2-160)
Multi-channel: modular piezo controller system E-500 (p. 2-142) with amplifier module E-503 (three channels) (p. 2-146) or E-505 (1 per axis, high-power) (p. 2-147) and E-509 controller (p. 2-152)
Single-channel digital controller: E-753 (bench-top) (p. 2-108)
Multi-channel digital controllers: E-710 bench-top (p. 2-128), E-712 modular (p. 2-140), E-725 high-power (p. 2-126), E-761 PCI board (p. 2-130)

N-510K High-Stiffness NEXLINE® Z Platform

High-Precision Positioning, with Capacitive Sensors

The N-510KHFS hybrid-drive nanopositioner offers maximum accuracy for semiconductor inspection applications

- **Self Locking at Rest, No Heat Generation**
- **Hybrid Drive: PiezoWalk® plus PICMA®**
- **Travel Range: 400 µm Coarse + 40 µm Fine**
- **2 µm Closed-Loop Resolution**
- **Direct Metrology:**
  One Single Control Loop with Capacitive Sensors
- **High Push and Holding Force to 25 N**
- **Piezo Walking Drive w/o Wear and Tear & Outstanding Lifetime due to PICMA® Piezo Actuators**

Model	Vertical travel	Velocity	Bidirectional repeatability	Load capacity	Dimensions
N-510KHFS Hybrid-Focus System	400 µm coarse 40 µm fine	1 mm/sec	50 nm (full travel)	25 N	Ø 300 mm 68.5 mm height

N-510 High-Force NEXLINE® Z/Tip/Tilt Platform

Nanometer Precision for Semiconductor Industry, Wafer Alignment

Z, tip, tilt nanopositioning platform with 3 integrated drives (tripod design)

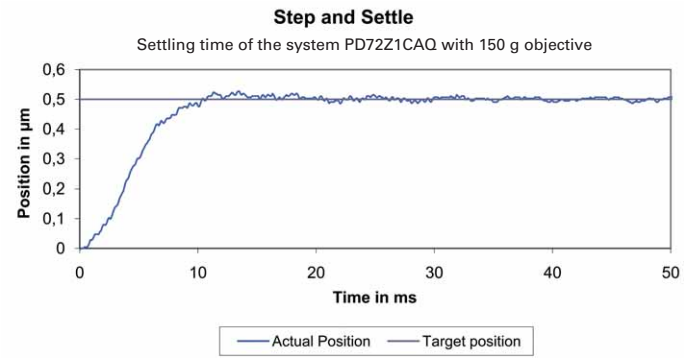
- **Self Locking at Rest, No Heat Generation**
- **Vacuum Compatible and Non-Magnetic Designs Feasible**
- **Parallel Kinematics for Enhanced Dynamics and Better Multi-Axis Accuracy**
- **NEXLINE® Piezo Walking Drive Free from Wear and Tear**
- **Load Capacity 200 N**
- **High Precision with Integrated 5 nm Incremental Sensors + Picometer Resolution Dithering Mode**

Model	Travel	Load capacity	Linear velocity	Dimensions
N-510 NEXLINE® Z, tip, tilt platform	1,3 mm vertical range 10 mrad tilt angle	200 N	0.2 mm/s	Ø 300 mm (12˝) Clear aperture 250 mm

Piezo Z-Objective Positioners

Affordable High Performance: With Digital Controller & Software

Several PIFOC® piezo objective scanners (fast focus mechanisms) with QuickLock thread adapter and digital controller (objective not included)



- **Complete System with Controller: Fast Digital Controller, Software-Configurable Servo Parameters**
- **Travel Ranges to 400 µm**
- **Scans and Positions Objectives with Sub-nm Resolution**
- **Frictionless, High-Precision Flexure Guiding System for Better Focus Stability**
- **Choice of SGS Sensor (Lower Cost) and Capacitive Feedback with Direct Metrology for highest Stability and Linearity**
- **Clear Aperture up to 29 mm Ø, QuickLock Adapter for Easy Attachment**
- **Interfaces: USB, RS-232 and analog**
- **Comprehensive Software Package, Compatible with MetaMorph Imaging Software**

The PIFOC® piezo objective scanner systems include a high precision piezo mechanism and a custom-tuned compact digital controller. This combination provides higher performance at reduced costs. The integrated, frictionless and stiff piezo flexure drive ensures high stiffness and fast settling times, as well as an exceptional guiding accuracy and response.
The settling time of less than 10 ms increases the throughput and allows rapid Z-stack acquisition.

Position Measurement with Highly Accurate Capacitive Sensors or Lower-Priced Strain Gauge Sensors

Capacitive sensors measure the position directly and without contact, they offer therefore a position resolution of far below one nanometer and excellent values in linearity.
As an alternative, compact and lower-priced strain gauge sensors (SGS) with nanometer-level resolution can be used which are applied to appropriate places on the drive train and thus measure the displacement of the moving part of the stage. The linearity is improved considerably with the digital controller provided.

N-725 PIFOC®
Objective nanofocusing system with 1 mm travel range

Simple Installation with QuickLock Thread Options

The PIFOC® is mounted between the turret and the objective with the QuickLock thread adapter. After threading the adapter into the turret, the QuickLock is affixed in the desired position. Because the PIFOC® body need not to be rotated, cable wind-up is not an issue. For applications which require a particularly large optical aperture a version with a 29 mm diameter threaded inserts is available.

Digital Controller for Automated Scans

Included in the delivery is a digital controller which opens up the possibilities of digital control for piezo-driven nanopositioning systems for the same price as analog controllers. The advantage: higher linearity, simple operation and access to advanced features.

Ordering Information

PD72Z1CAA
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, Capacitive Sensor, M32 Large Aperture QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z1CAQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, Capacitive Sensor, M25 QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z1SAA
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, SGS Sensor, M32 Large Aperture QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z1SAQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 100 µm, SGS Sensor, M25 QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z2CAA
Fast PIFOC® Piezo Nanofocusing Z-Drive, 250 µm, Capacitive Sensor, M32 Large Aperture QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z2CAQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 250 µm, Capacitive Sensor, M25 QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z4CAA
Fast PIFOC® Piezo Nanofocusing Z-Drive, 400 µm, Capacitive Sensor, M32 Large Aperture QuickLock Thread Adapters, Digital Controller with USB, RS-232

PD72Z4CAQ
Fast PIFOC® Piezo Nanofocusing Z-Drive, 400 µm, Capacitive Sensor, M25 QuickLock Thread Adapters, Digital Controller with USB, RS-232

Program Overview

- Piezo Ceramic Actuators & Motors
- Piezo Nanopositioning Systems and Scanners
- Active Optics / Tip-Tilt Platforms
- Capacitive Nanometrology Sensors
- Piezo Electronics: Amplifiers and Controllers
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FRANCE

PI France S.A.S
244 bis, avenue Max Dormoy
92120 Montrouge
Tel: +33 (1) 55 22 60 00
Fax: +33 (1) 41 48 56 62
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www.pi-france.fr

ITALY

Physik Instrumente (PI) S.r.l.
Via G. Marconi, 28
I-20091 Bresso (MI)
Tel: +39 (02) 665 011 01
Fax: +39 (02) 873 859 16
info@pionline.it
www.pionline.it

GERMANY

Physik Instrumente (PI) GmbH & Co. KG
Auf der Römerstr. 1
D-76228 Karlsruhe/Palmbach
Tel: +49 (721) 4846-0
Fax: +49 (721) 4846-100
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